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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

HATADA et al

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Serial No. 10/743,409

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Examiner:

For: GAS CONCENTRATION MEASURING APPARATUS

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January 22, 2007

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT

Attention is directed to the attached Japanese Office Action (and English translation) in a counterpart of this application and to a copy of each non-US patent document newly cited therein. A Form PTO/SB/08a is also attached.

Official consideration and citation of all identified documents is requested.

Respectfully submitted,

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